# **Positron Annihilation for Materials Science & The intense Positron Source EPOS**



### **R. Krause-Rehberg**

Univ. Halle



Martin-Luther-Universität Halle-Wittenberg

- Why are nano-defects important at all?
- Positron trapping by defects
- Positronium to probe pores
- New positron facilities the EPOS Project



### **Point defects determine properties of materials**

- Point defects determine electronic and optical properties
- electric conductivity strongly influenced
- Doping of semiconductors (n-, p-Si)



- Point defects are generated by irradiation (e.g. cosmic rays), by plastic deformation or by diffusion, ...
- Metals in high radiation environment -> formation of voids -> embrittlement
- -> Properties of vacancies and other point defects must be known
- Analytical tools are needed to characterize point defects



# The positron lifetime spectroscopy

<sup>22</sup>Na



- positron wave-function can be localized in the attractive potential of a defect
- annihilation parameters change in the localized state
- e.g. positron lifetime increases in a vacancy
- lifetime is measured as time difference between appearance of 1.27 (start) and 0.51 MeV (stop) quanta
- defect identification and quantification possible



#### The positron lifetime spectroscopy - conventional setup



Positron lifetime: time between 1.27 MeV and 0.511 MeV quanta



# **Digital lifetime measurement**



- much simpler setup
- timing very accurate (<10<sup>-6</sup> instead of 5x10<sup>-3</sup>)
- pulse-shape discrimination (suppress "bad pulses"): better time resolution
- each detector for start & stop (double statistics)



### Screenshot of two digitized anode pulses

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#### **Positron lifetime spectroscopy**



- positron lifetime spectra consist of exponential decay components
- positron trapping in open-volume defects leads to long-lived components
- longer lifetime due to lower electron density
- analysis by non-linear fitting: lifetimes  $\tau_i$  and intensities  $\mathbf{I}_i$

positron lifetime spectrum:

$$N(t) = \sum_{i=1}^{k+1} \frac{I_i}{\tau_i} \exp\left(-\frac{t}{\tau_i}\right)$$

trapping coefficient

$$\kappa_{\rm d} = \mu C_{\rm d} = \frac{I_2}{I_1} \left( \frac{1}{\tau_{\rm b}} - \frac{1}{\tau_{\rm d}} \right)$$

trapping rate

defect concentration



#### **Vacancies in thermal Equilibrium**



### **Defects in Iron after tensile strength and fatigue treatment**

- We performed an extensive study of defects in mechanically damaged iron and steel
- Positrons are very sensitive: detection of defects already in the Hooks range of the stress-strain experiment
- Vacancy cluster and dislocations are detectable in both cases



#### **Defects in electron-irradiated Ge**

- Electron irradiation (2 MeV @ 4K) induces Frenkel pairs (vacancy interstitial pairs)
- steep annealing stage at 200 K
- at high irradiation dose: divacancies are formed (thermally more stable)



#### **Electron irradiation of Si**

- low-temperature electron irradiation was performed at 4K (E<sub>e-</sub>=2 MeV)
- annealing stage of monovacancies at about 170 K
- moving V<sub>si</sub> partly form divacancies
- divacancies anneal at about 550...650 K





Polity et al., Phys. Rev. B 58 (1998) 10363





## Sensitivity limits of PAS for vacancy detection

- lower sensitivity limit e.g. for negatively charged divacancies in Si starts at about 10<sup>15</sup> cm<sup>-3</sup>
- **upper limit**: saturated positron trapping
- defect identification still possible
- Then: only lower limit for defect density can be given





- in a metal: charge of a vacancy is effectively screened by free electrons
- they are not available in semiconductors
- thus, long-range Coulomb potential added
- positrons may be attracted or repelled
- trapping coefficient  $\mu$  is function of charge state



#### **GaAs: annealing under defined As-partial pressure**



#### **GaAs: Annealing under defined As pressure**

Si<sub>Ga</sub>-V<sub>Ga</sub>

Te<sub>As</sub>-V<sub>Ga</sub>



#### **Comparison of doped and undoped GaAs**





Bondarenko et al., 2003



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### **Identification of V<sub>Ga</sub>-Si<sub>Ga</sub>-Complexes in GaAs:Si**





#### Vacancy clusters in semiconductors

- vacancy clusters were observed after neutron irradiation, ion implantation and plastic deformation
- due to large open volume (low electron density) -> positron lifetime increases distinctly

Vacancy clustering

- example: plastically deformed Ge
- defect lifetime:  $\tau$  = 525 ps
- reason for void formation: jog dragging mechanism
- trapping rate of voids disappears during annealing experiment

Jog







Screw

dislocation

### **Theoretical calculation of vacancy clusters in Si**



- there are cluster configurations with a large energy gain
- "Magic Numbers" with 6, 10 und 14 vacancies
- positron lifetime increases distinctly with cluster size
- for n > 10 saturation effect, i.e. size cannot be determined

T.E.M. Staab et al., Physica B 273-274 (1999) 501-504



#### **Typical Lifetimes**



### **Principles of PALS: ortho-Positronium**

In materials without free electrons Positronium may be formed (Polymers, glass, liquids, gases).





### **Pick-off annihilation**

#### pick-off annihilation:

- o-Ps is converted to p-Ps by capturing an electron with anti-parallel spin
- happens during collisions at walls of pore
- lifetime decreases rapidly
- lifetime is function of pore size 1.5 ns to 142 ns







### o-Ps lifetime $\tau_4$ versus pore size



 we measured porous CPG glass in a broad pore size range



- given pore size obtained by N<sub>2</sub>-adsorption and/or mercury intrusion technique
- for T=300 K fair agreement to the RTE model for large pores

RTE model: D. W. Gidley, T. L. Dull, W. E. Frieze, J. N. Sun, A. F. Yee, J. Phys. Chem. B 2001, 105, 4657.



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### Lateral Resolution with Positron-Scanning-Microscope

- lateral resolution 2 μm
- Positron lifetime spectroscopy
- however lateral resolution principally limited by positron diffusion (L\_\*  $\approx$  100nm)
- problem: low count rate
- transfer to FRM-II



W. Triftshäuser et al., NIM B 130 (1997) 265

#### **Microhardness indentation in GaAs**

 Comparison of SEM and Munich Positron Scanning Microscope

- problem here at the moment: intensity
- hope: strong positron source at FRM-II
   Garching or EPOS project in Rossendorf





### **EPOS** = **ELBE Positron Source**

- ELBE -> electron LINAC (40 MeV and up to 40 kW) in Research Center Dresden-Rossendorf
- EPOS will be the combination of a positron lifetime spectrometer, Doppler coincidence, and AMOC
- user-dedicated facility
- main features:
  - high-intensity bunched positron beam ( $E_{+}$  = 0.5...30 keV)
  - very good time resolution by using the unique primary time structure of ELBE
  - high quality spectra by lifetime and Doppler spectroscopy in coincidence mode
  - very high count rate by multi-detector array
  - all spectrometers digital
  - conventional source included for Doppler measurements (when primary beam is not available)
  - fully remote control via internet by user



### **Ground plan of the ELBE hall**







### beam line to positron source

#### beam line to neutron hall

### Water cooling system

Cave 111b

### **EPOS - Applications**

#### Variety of applications in all field of materials science:

- defect-depth profiles due to surface modifications and ion implantation
- tribology (mechanical damage of surfaces)
- polymer physics (pores; interdiffusion; ...)
- low-k materials (thin high porous layers)
- defects in semiconductors, ceramics and metals
- epitaxial layers (growth defects, misfit defects at interface, ...)
- fast kinetics (e.g. precipitation processes in Al alloys; defect annealing; diffusion; ...)
- radiation resistance (e.g. space materials)
- many more ...



## Conclusions

- Positrons are a unique tool
  - for characterization of vacancy-type defects in crystalline solids
  - for embedded nano-particles (e.g. small precipitates)
  - for nano-porosimetry
- New facilities become available for user-dedicated operation having
  - better time resolution and spectra quality
  - lateral resolution 1 μm
  - much higher intensity

This presentation can be found as pdf-file on our Website: http://positron.physik.uni-halle.de

contact: mail@KrauseRehberg.de

